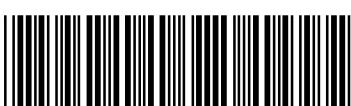


<b>Search Notes</b>	<b>Application/Control No.</b>	<b>Applicant(s)/Patent Under Reexamination</b>
	10667368	NOGUCHI, TAKAFUMI
	<b>Examiner</b>	<b>Art Unit</b>
	Choi, Jacob Y	2885

## SEARCHED

<b>Class</b>	<b>Subclass</b>	<b>Date</b>	<b>Examiner</b>
362	2, 602, 606, 617-620, 84, 34, 166, 230, 231, 244, 293, 326, 330	10/20/2005	JC

## SEARCH NOTES

<b>Search Notes</b>	<b>Date</b>	<b>Examiner</b>
Class/Subclass & Text Search Conducted by Examiner (including class 359)	10/20/2005	JC
Updated Search Conducted by Examiner	8/29/2006	JC
Updated Search Conducted by Examiner	2/14/2007	JC
STIC Search was performed by M. Mims (e.g., diffracting grating range)	02/6/2007	JC
Updated Search Conducted by Examiner	8/22/2007	JC
Updated Search Conducted by Examiner	3/14/2008	JC
Updated search, Assignment data search, Inventor name search, Back/Forward search	12/10/2008	JC
Updated search	7/14/2009	JC
Updated search	11/30/2009	JC

## INTERFERENCE SEARCH

<b>Class</b>	<b>Subclass</b>	<b>Date</b>	<b>Examiner</b>
PG pub text search	See interference search printout	11/30/2009	JC

	/JACOB Y CHOI/ Primary Examiner.Art Unit 2885
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